

(FILE 'USPAT' ENTERED AT 10:47:48 ON 25 AUG 1999)

SET HIGH OFF

L1 50301 S (LIQUID CRYSTAL OR LCD#)

SET HIGH ON

L2 5144 S PIXEL(P) REFLECT?

L3 127 S L2 AND (GUEST(W) HOST)

L4 1 S 5805252/PN

L5 1 S L4 AND DYE

L6 125 S L3 AND L1

## SUMMARY:

BSUM(14)

Also, the method for manufacturing a mask for forming the orientation layer comprises the steps of: forming a predetermined metal pattern on a transparent substrate in a striped pattern; forming a plurality of hemicircular metal patterns in parallel by heating rectangular metal patterns formed on the substrate in the metal pattern forming step in a predetermined temperature, simultaneously irradiating the metal patterns to be molten with a light having a predetermined energy per unit space and cooling the metal patterns; forming a hemicircular microlens array formed of a compact oxide layer from the substrate processed in the metal pattern forming step, by oxidizing the metal patterns using an **anode** oxidation method; forming a light-blocking layer between the microlenses formed in the oxidizing step by coating a highly **reflective** material using a thin film forming method; and forming an anti-**reflection** coating layer on an opposing plane of the substrate whereon the light-blocking layer is formed.